

# Large-area $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diode and its application in DC–DC converters

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**Abstract:** We demonstrate superb large-area vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBDs with a Schottky contact area of  $1 \times 1$  mm<sup>2</sup> and obtain a high-efficiency DC–DC converter based on the device. The  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD can obtain a forward current of 8 A with a forward voltage of 5 V, and has a reverse breakdown voltage of 612 V. The forward turn-on voltage ( $V_F$ ) and the on-resistance ( $R_{on}$ ) are 1.17 V and 0.46  $\Omega$ , respectively. The conversion efficiency of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC–DC converter is 95.81%. This work indicates the great potential of Ga<sub>2</sub>O<sub>3</sub> SBDs and relevant circuits in power electronic applications.

**Key words:**  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>; SBD; DC–DC converter

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## 1. Introduction

Power devices and circuits are the most important parts of the electrical energy conversion system. Meanwhile, power devices and circuits based on ultra-wide bandgap semiconductors can contribute to reducing the power consumption in the conversion<sup>[1]</sup>.

$\beta$ -Ga<sub>2</sub>O<sub>3</sub> is considered to have great potential in power electronic applications due to its wide bandgap of approximately 4.8 eV, high critical electric field of 8 MV/cm and high Baliga's figure of merit of 3444<sup>[2–4]</sup>. These properties make  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> power devices promising for high voltage, high power and other applications<sup>[5, 6]</sup>.

In the past decade,  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> devices, especially Schottky barrier diodes (SBDs), have developed rapidly, whose performances have been improved significantly and currently approach those of SiC and GaN<sup>[7–12]</sup>. At present, the works of large-area devices mainly focus on the combination with edge termination<sup>[13–16]</sup>, while the baseline devices or named termination-free SBDs are rarely investigated for large-current applications. Our recent work demonstrated that the performance of small-area SBDs can be greatly improved by interface engineering<sup>[11]</sup>, thus it is a chance for large-area devices. The high-performance SBDs with free termination may better reflect the application potential of Ga<sub>2</sub>O<sub>3</sub> SBD. In a word, the Ga<sub>2</sub>O<sub>3</sub> SBD is more mature for applications and needs to be further demonstrated for its application potential.

In this work, we achieved a high-performance large-area vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD with a Schottky contact area of  $1 \times 1$  mm<sup>2</sup>, and then realized its application in a DC–DC converter with high efficiency. The  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD obtained good forward characteristics of 8 A@5 V, a low  $R_{on}$  of 0.46  $\Omega$  and a high breakdown voltage ( $V_{br}$ ) of 612 V. A prototype of the DC–DC converter is demonstrated using the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD, then a conversion efficiency of 95.81% is obtained.

## 2. Device fabrication and characterization

The schematic cross section and optical image of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD are shown in Fig. 1. The Ga<sub>2</sub>O<sub>3</sub> substrate has a doping concentration about  $7.0 \times 10^{18}$  cm<sup>-3</sup> with a thickness of 610  $\mu$ m, and the 8.5  $\mu$ m-thick Ga<sub>2</sub>O<sub>3</sub> epitaxial layer grown by halide vapor phase epitaxy (HVPE) has a doping concentration of approximately  $1.9 \times 10^{16}$  cm<sup>-3</sup>. After organic and acid cleaning, the upper surface of the epitaxial layer is removed by ICP180 to remove the unreliable surface<sup>[11]</sup>. Following the piranha solution, the backside of the Ga<sub>2</sub>O<sub>3</sub> substrate is coated with Ti/Al/Ni/Au (20/200/50/50 nm) metal stacks by electron beam evaporation (E-beam), and then undergoes rapid thermal annealing at 470  $^{\circ}$ C in N<sub>2</sub> for 1 min to improve ohmic contact. The Schottky electrode with Ni/Au (50/100 nm) is deposited by the E-beam system. The Schottky contact area of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD is  $1 \times 1$  mm<sup>2</sup>.

Fig. 2(a) shows the forward conduction characteristics of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD. The forward turn-on voltage ( $V_F$ ) and the on-resistance ( $R_{on}$ ) are 1.17 V and 0.46  $\Omega$ , respectively. A forward current of 8 A can be obtained at a forward voltage of 5 V in pulse mode (50- $\mu$ s pulse width and 1% duty cycle). Meanwhile, the  $V_{br}$  of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD is 612 V as shown in Fig. 2(b).

The performance of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD is benchmarked against some reported state-of-the-art large-area  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBDs with electrode areas above 0.2 mm<sup>2</sup> in the plot of  $R_{on,sp}$  versus  $V_{br}$  in Fig. 3<sup>[9, 16–19]</sup>. The specific on-resistance ( $R_{on,sp}$ ) is 4.6 m $\Omega$ ·cm<sup>2</sup>. Associated with the  $V_{br}$  of 612 V, the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD presents a FOM of 81.4 MW/cm<sup>2</sup>. Compared with the reported work, the fabricated  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD in this work exhibits superior performance.

In order to judge the relative performance of the device with the commercial SBDs based on Si and SiC, and to quantify the remaining gap to be closed in the future, we compared our  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD with the commercial Si FRD (STTH1L06, 600 V/1 A) and SiC SBD (CSD01060A, 600 V/1 A) as shown in Table 1. From the results, we can obtain that our  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD shows a comparable performance with commercial Si FRD and SiC SBD, while the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> device is just in its

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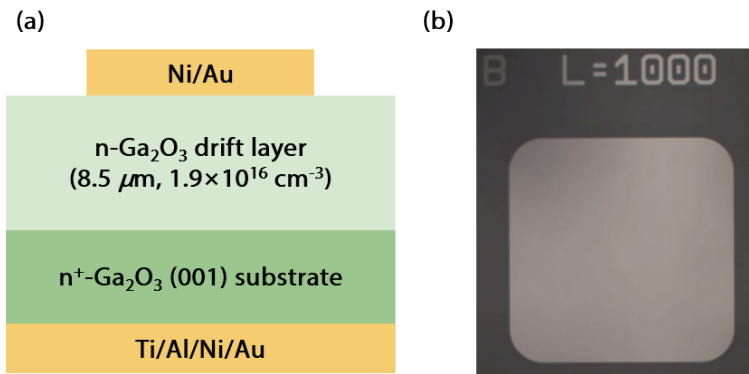


Fig. 1. (Color online) (a) Schematic cross section of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD. (b) Optical image.

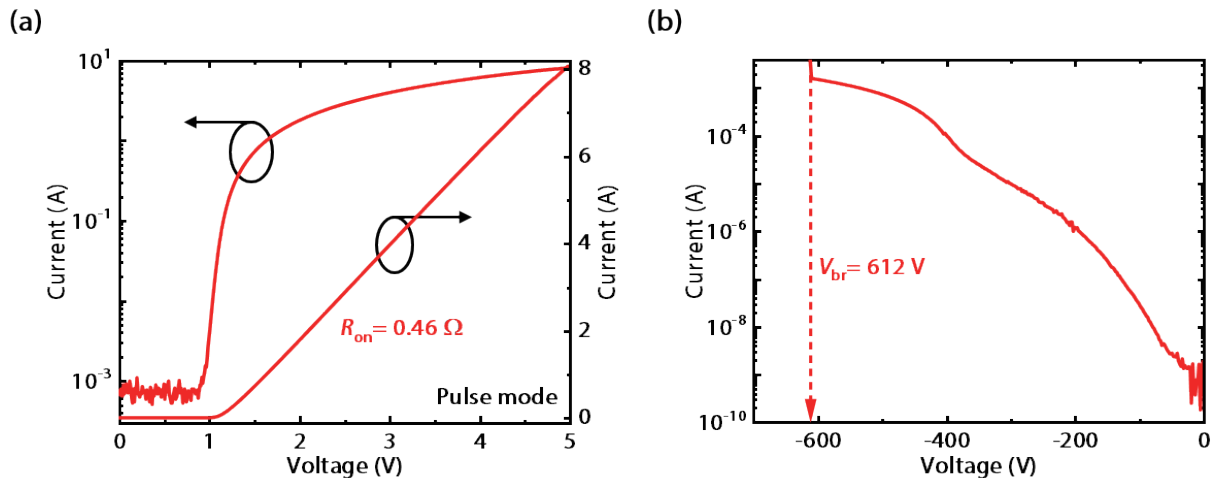


Fig. 2. (Color online) (a) Forward conduction characteristics and (b) reverse breakdown characteristics of the  $1 \times 1$  mm<sup>2</sup>.

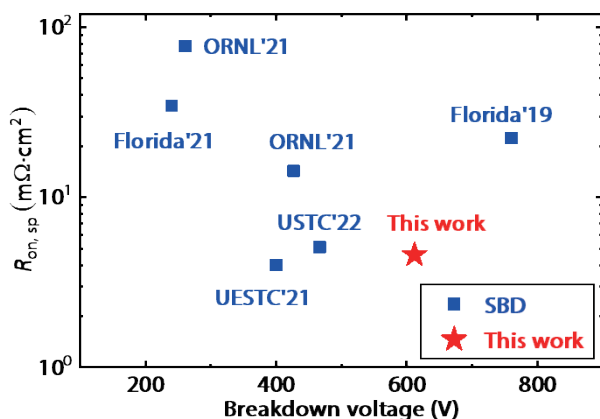


Fig. 3. (Color online)  $R_{on,sp}$  versus  $V_{br}$  benchmarks of reported state-of-the-art large-area  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBDs with electrode areas above 0.2 mm<sup>2</sup>.

infancy. Reducing the on-resistance and increasing the breakdown voltage are still the key points of our work in future development.

A double-pulse test (DPT) circuit was designed to evaluate the switching performance of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD<sup>[16]</sup>, and the reverse recovery characteristic of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD was measured when the device switched from a forward current of 1 A to a reverse bias voltage of 100 V with a  $di/dt$  of 500 A/ $\mu$ s. The reverse recovery characteristics of the Si FRD, SiC SBD and  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD are contrasted in Fig. 4, and the properties of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> with commercial Si and SiC devices are shown in Table 1. We can obtain from the experimental results that the

Table 1. Properties of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> with commercial Si and SiC devices.

Parameters	Si FRD	SiC SBD	$\beta$ -Ga <sub>2</sub> O <sub>3</sub> SBD
$R_{on}$ ( $\Omega$ )	0.17	0.38	0.46
$V_{br}$ (V)	663	776	612
$I_{rr}$ (A)	3.61	1.54	1.9
$t_{rr}$ (ns)	16.9	6.8	7.4
$Q_{rr}$ (nC)	38.34	6.50	8.69

reverse recovery characteristic of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD has an apparent advantage over Si FRD and approaches to SiC SBD.

### 3. Application in the DC-DC converter

In order to demonstrate the application potential, the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD is encapsulated in the TO-220 package, and then implemented in a DC-DC converter circuit. The circuit configuration of the converter is shown in Fig. 5, and the specifications of the converter are summarized in Table 2.

A 650 V/180 m $\Omega$  discrete GaN FET with part number TPH3206PSB (Transphorm) is used for switching control. The gate driver of Si8261 (Skyworks) is used to drive the GaN FET, and the gate-source voltage ( $V_{GS}$ ) is +9 V during the on-state and 0 V during the off-state. The input voltage ( $V_{IN}$ ) is selected to be 200 V, and the converter is operated at a switching frequency ( $f$ ) of 100 kHz and a duty cycle ( $D$ ) of 40%.

Fig. 6 shows the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter and the testing platform. The square signal for the gate driver was generated by an arbitrary function waveform gener-

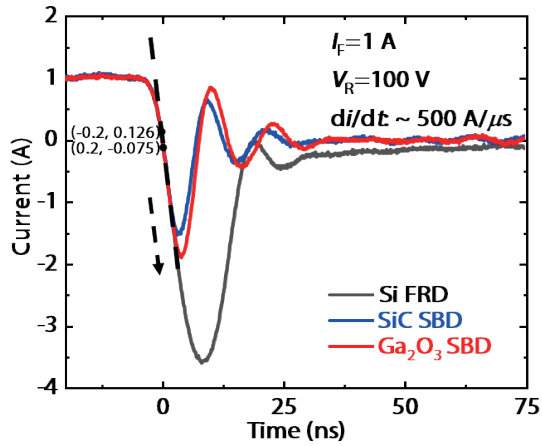


Fig. 4. (Color online) The reverse recovery characteristics of the Si FRD, SiC SBD and  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD.

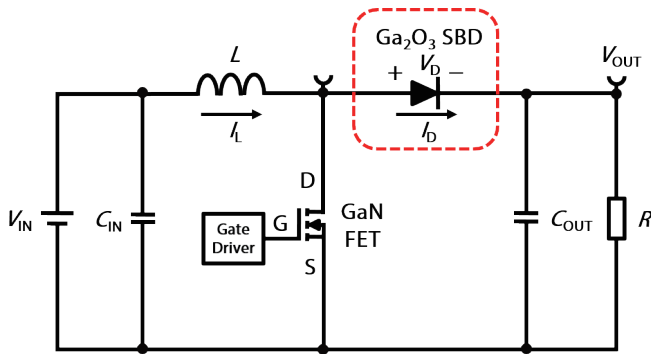


Fig. 5. (Color online) Schematic of the DC-DC converter based on the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD.

Table 2. Specifications of the DC-DC converter.

Parameters	Values	Parameters	Values
GaN FET	650 V/180 m $\Omega$	$L$ (mH)	1
$V_{IN}$ (V)	200	$f$ (kHz)	100
$C_{IN@315V}$ ( $\mu$ F)	100	$D$	40%
$C_{OUT@500V}$ ( $\mu$ F)	6.8	$R$ (k $\Omega$ )	1

Table 3. Experimental results of the DC-DC converter.

Parameters	Values	Parameters	Values
$V_{IN}$ (V)	200	$P_{IN}$ (W)	115.28
$V_{AUX}$ (V)	9	$P_{OUT}$ (W)	110.45
$V_{OUT}$ (V)	329.7	Efficiency	95.81%

ator (Keysight, 33600A), and the auxiliary voltage for the gate driver ( $V_{AUX}$ ) was provided by a DC power supply (ITECH, IT6333C). The input voltage ( $V_{IN}$ ) was generated by an auto range DC power supply (ITECH, IT6526C), and the output signal ( $V_{OUT}$ ) was tested through a DC electronic load (ITECH, IT8902E). The voltage and current waveforms were monitored by an oscilloscope (Keysight, MSOX6004A).

The experimental waveforms of the gate-source voltage ( $V_{GS}$ ), the output voltage ( $V_{OUT}$ ), the inductor current ( $I_L$ ), the diode voltage ( $V_D$ ) and the diode current ( $I_D$ ) in the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter are shown in Figs. 7 and 8. The spike in the waveform of the diode current ( $I_D$ ) is due to the reverse recovery characteristics of the SBD. The experimental results are shown in Table 3, the output voltage of the converter is approximately 329.7 V, and the output voltage rip-

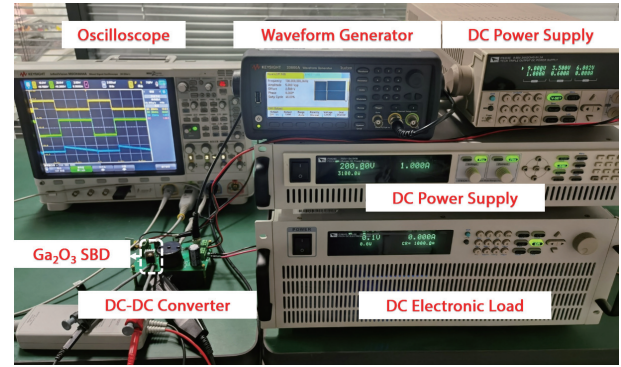


Fig. 6. (Color online) Photograph of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter and the testing platform.

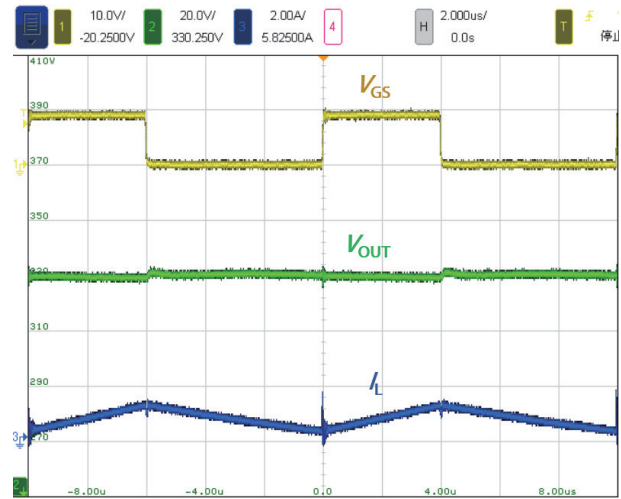


Fig. 7. (Color online) Experimental waveforms of the  $V_{GS}$ ,  $V_{OUT}$  and  $I_L$  in the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter.

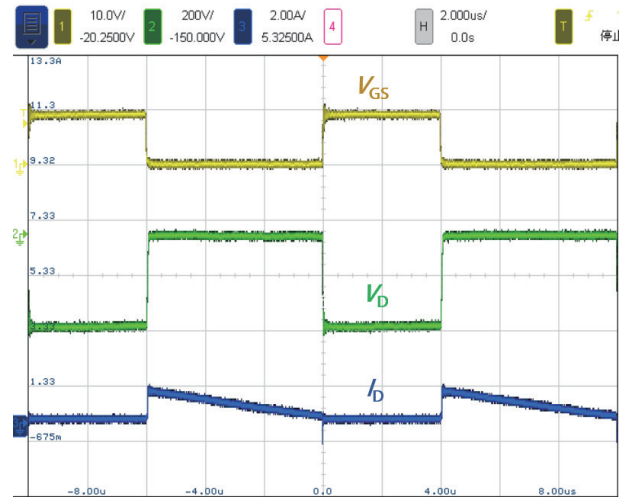


Fig. 8. (Color online) Experimental waveforms of the  $V_{GS}$ ,  $V_D$  and  $I_D$  in the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter.

ple is less than 0.5%. The conversion efficiency of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC-DC converter is 95.81%.

#### 4. Conclusion

In conclusion, we have achieved a high-performance large-area vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD with a Schottky contact area of 1  $\times$  1 mm<sup>2</sup> and obtained a high-efficiency DC-DC converter based on the device. The  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD can obtain a for-

ward current of 8 A at a forward voltage of 5 V, and has a  $V_{br}$  of 612 V. The conversion efficiency of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> SBD-based DC–DC converter is 95.81%. The decent performance of Ga<sub>2</sub>O<sub>3</sub> SBDs and their circuits shows great potential in power electronic applications. Future works will introduce the edge termination technique to this baseline device.

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## References

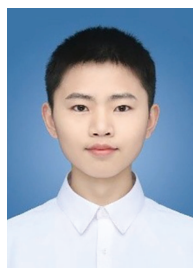
- [1] Baliga B J. Fundamentals of power semiconductor devices. Cham: Springer International Publishing, 2019
- [2] Sasaki K, Higashiwaki M, Kuramata A, et al. Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diodes fabricated by using single-crystal  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> (010) substrates. *IEEE Electron Device Lett*, 2013, 34, 493
- [3] Higashiwaki M, Sasaki K, Kuramata A, et al. Gallium oxide (Ga<sub>2</sub>O<sub>3</sub>) metal-semiconductor field-effect transistors on single-crystal  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> (010) substrates. *Appl Phys Lett*, 2012, 100, 013504
- [4] Pearton S J, Yang J C, Cary P H IV, et al. A review of Ga<sub>2</sub>O<sub>3</sub> materials, processing, and devices. *Appl Phys Rev*, 2018, 5, 011301
- [5] Pearton S J, Ren F, Tadjer M, et al. Perspective: Ga<sub>2</sub>O<sub>3</sub> for ultra-high power rectifiers and MOSFETS. *J Appl Phys*, 2018, 124, 220901
- [6] Ren F, Yang J C, Fares C, et al. Device processing and junction formation needs for ultra-high power Ga<sub>2</sub>O<sub>3</sub> electronics. *MRS Commun*, 2019, 9, 77
- [7] Konishi K, Goto K, Murakami H, et al. 1-kV vertical Ga<sub>2</sub>O<sub>3</sub> field-plated Schottky barrier diodes. *Appl Phys Lett*, 2017, 110, 103506
- [8] Zhou H, Yan Q L, Zhang J C, et al. High-performance vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diode with implanted edge termination. *IEEE Electron Device Lett*, 2019, 40, 1788
- [9] Ji M, Taylor N R, Kravchenko I, et al. Demonstration of large-size vertical Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diodes. *IEEE Trans Power Electron*, 2020, 36, 41
- [10] Li W S, Nomoto K, Hu Z Y, et al. Field-plated Ga<sub>2</sub>O<sub>3</sub> trench Schottky barrier diodes with a  $BV^2/R_{on,sp}$  of up to 0.95 GW/cm<sup>2</sup>. *IEEE Electron Device Lett*, 2020, 41, 107
- [11] He Q M, Hao W B, Zhou X Z, et al. Over 1 GW/cm<sup>2</sup> vertical Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diodes without edge termination. *IEEE Electron Device Lett*, 2022, 43, 264
- [12] Yang J C, Ren F, Chen Y T, et al. Dynamic switching characteristics of 1 A forward current  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> rectifiers. *IEEE J Electron Devices Soc*, 2018, 7, 57
- [13] Lv Y J, Wang Y G, Fu X C, et al. Demonstration of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> junction barrier Schottky diodes with a Baliga's figure of merit of 0.85 GW/cm<sup>2</sup> or a 5A/700 V handling capabilities. *IEEE Trans Power Electron*, 2021, 36, 6179
- [14] Otsuka F, Miyamoto H, Takatsuka A, et al. Large-size (1.7 × 1.7 mm<sup>2</sup>)  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> field-plated trench MOS-type Schottky barrier diodes with 1.2 kV breakdown voltage and 10<sup>9</sup> high on/off current ratio. *Appl Phys Exp*, 2022, 15, 016501
- [15] Hao W B, Wu F H, Li W S, et al. High-performance vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diodes featuring P-NiO JTE with adjustable conductivity. 2022 International Electron Devices Meeting (IEDM).

San Francisco, CA, USA. *IEEE*, 2023, 9.5.1

- [16] Guo W, Jian G Z, Hao W B, et al.  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> field plate Schottky barrier diode with superb reverse recovery for high-efficiency DC–DC converter. *IEEE J Electron Devices Soc*, 2022, 10, 933
- [17] Wei Y X, Luo X R, Wang Y G, et al. Experimental study on static and dynamic characteristics of Ga<sub>2</sub>O<sub>3</sub> Schottky barrier diodes with compound termination. *IEEE Trans Power Electron*, 2021, 36, 10976
- [18] Yang J C, Fares C, Elhassani R, et al. Reverse breakdown in large area, field-plated, vertical  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> rectifiers. *ECS J Solid State Sci Technol*, 2019, 8, Q3159
- [19] Sharma R, Xian M H, Fares C, et al. Effect of probe geometry during measurement of >100 A Ga<sub>2</sub>O<sub>3</sub> vertical rectifiers. *J Vac Sci Technol A*, 2021, 39, 013406



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